Advances in structural, electrical and optoelectronic characterization of thin nanocrystalline silicon films for photovoltaic applications

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NANDcrystalline silicon films for



Outline

- Materials
- Methods and Results
 - Structural Characterization
 - Stress measurements and transmission electron microscopy)
 - Atomic Force Microscopy XRD, Raman spectroscopy, and FTIR
 - Electrical characterization
 - · C-AFM
 - Conductivity
 - Optoelectronic characterization
 - SPV (Surface Photovoltage Spectroscopy)
 Photoluminescence measurements and Quantum confinement studies
- Conclusions

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Materials

nc-Si:H grown by

Low Energy Plasma Enhanced Chemical Vapour Deposition (LEPECVD)

Substrate	X _c [%]	Ts[°C]	†[mm]	Growth rate [nm/s]
SiO ₂ /Si	65 ÷ 70%	<mark>208</mark> ÷ 280	1.5 ÷ 1.7	0.17 ÷ 1
Si	10 ÷ 50%	280	1 ÷ 2	2.5 ÷ 3.5
Glass & Glass/ITO	13 ÷ 80	250	1 ÷ 4	3.1 ÷ 4.3



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SiO₂/Si substrates

In all the specimens the structure is similar, whatever the growth parameters



Si substrates

Cross section view: intermediate magnification TEM observations For all the specimens, the structure is **heterogeneous** along the growth direction





20 nm

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<u>Si substrate</u> Structural changes along the growth direction : 3 domains...



Substrate Glass X-HRTEM observations : nc-Si layers contain numerous columnar nanocrystals Twins are frequently observed



5 nm

5 nm



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Substrate Glass

HRTEM observations in plan-view: Diameter and shape of nanocrystalline columns are variable



2 nm





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Atomic Force Microscopy

AGS (Average grain size) values: [100-200] nm





Average Height: [10-20] nm RMS: [2-6] nm



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Sub	strate	Roughness (nm)	
SiO ₂ /S	5i and Si	2÷6	
Glass		4÷5	
ITO	/Glass	20 ÷ 40	
Constant	The roughness • depends on sample thickness • is almost independent of crystallinity • depends mainly on substrate		

XRD results

Orientation:

dominant growth direction <111> for all three substrates

Average grain dimension:

• tens of nm with SiO₂/Si & Si substrates independently of the silane dilution,

• from tens of nm at high silane dilution (d \ge 30 %) to few nm at low silane dilution (d < 30 %) with glass substrate





• Transizione $c \rightarrow a$

Conductivity-AFM The probe scans the sample in contact mode.



A feedback loop keeps the cantilever

deflection constant by varying the tipsample distance.

At the same time a bias potential (3V) is applied to the probe and <u>the electrical</u> <u>current is measured</u>.

C-AFM Transport Mectopernissing cumentions simultaneously



The localization of the charge trasport is still an open problem:

Route 1 and *Route 2* represent two possibilities supported by experimental data [1,2].

[Route 1, I.Balberg et al., Phys. Rev. B 71 (2005)] [Route 2, A.Fejfar et al., J. Non-Cryst. Solids 266-269 (2000)]

C-AFM. Results



The conduction occurs through charge transport across the nanograins This result has been obtained <u>in all the samples.</u>

Conductivity

 Low dark conductivity ≈ 10⁻⁷ Ohm⁻¹cm⁻¹ for all the samples (good candidate as i- layer for p-i-n cells)

 High photosensitivity ≈ 100 for the samples grown on glass, promising for PV applications

substrates SiO₂/Si and Si

SPS: Results



Quantum confinement

- correlation between crystallinity and intensity of the photoluminescence \rightarrow band A

candidate for emission due to quantum confinement???

• its energy position between the c-Si and the a-Si gaps.



band A observed also in a-Si:H samples and attributed to <u>localized states</u> in the amorphous matrix.

Quantum confinement



about the intensity: Energy (eV)

PL spectra from regions with different crystallinity Xc origin of the intensity? origin of the shape?

intensity of band A increases as the crystallinity of the film decreases possible explanations:

- band A is due to <u>small</u> NCs \rightarrow its intensity decreases when the average NC <u>size increases</u> with crystallinity;
- band A is related to the $\alpha\text{-phase}\to\text{its}$ intensity decreases when the relative volume of the amorphous phase decreases in high crystallinity samples

about the shape:

the A band lineshape seems to be determined by the <u>size</u> of the NCs

Conclusions

What do we know about nc-Si:H?

- Substrate and temperature significantly influence the microstructure (TEM) and the surface properties (roughness, AFM)
- The electrical conduction occurs through the nanograins (C-AFM)
- Samples grown on glass show high photogain, very promising for PV applications
- Optical properties are strongly linked to crystallinity (SPS)
- Optical confinement is likely related to the band A, the origin of which is linked to the crystallinity wherever the responsible localized states are

thank you for your attention





Task 3.1 : Stress measurements and transmission electron microscopy results



Series I main features : Low mag, HR & X-HR TEM observations

For all the specimens, the structure is similar, whatever the growth parameters









Task 3.1 : Stress measurements and transmission electron microscopy results

Series II Microstructure far from the interface : from crystalline to amorphous transition

